

PATENT
8075-1099

IN THE U.S. PATENT AND TRADEMARK OFFICE

In re application of

Yasuhiko KASAMA et al. Conf. 9603

Application No. 10/585,245 Group 1792

Filed January 10, 2007

Examiner Marianne L. Padgett

ION IMPLANTATION SYSTEM AND ION IMPLANTATION SYSTEM

INFORMATION DISCLOSURE STATEMENT

Commissioner for Patents September 25, 2009
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

In compliance with Rules 1.97 and 1.98, and in fulfillment of the duty of disclosure under Rule 1.56, the accompanying documents, copies of which are attached to this statement, are made of record on the enclosed Form PTO-1449.

A concise explanation of the relevance of these items is that these references were cited by the Korean Patent Office in the corresponding Korean Application filed July 9, 2007.

If necessary, the Commissioner is hereby authorized in this, concurrent, and future submissions, to charge any underpayment or credit any overpayment to Deposit Account

No. 25-0120 for any additional fees required under 37 C.F.R.
§ 1.16 or under 37 C.F.R. § 1.17.

Respectfully submitted,

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